The 21st Korean Conference on Semiconductors
# 제21회 한국반도체학술대회
February 24-26, 2014 / Hanyang University, Seoul, Korea

Q. Metrology, Inspection, and Yield Enhancement 분과

## [WD4-Q] Metrology and Inspection

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| **Date** | Feb. 26, 2014 (Wed.) |
| **Place** | Room D / 제1공학관 402호 (# 402, Engineering Building I) |

Session Chair: 유형원 수석(SK hynix), 김호섭 교수(선문대학교)

**WD4-Q-1** **17:15-17:45**

**WD4-Q-2** **17:45-18:00** **Wafer Defect Inspection by Multi-Level Thresholding of SEM Images**

저자: Sunghyon Kim[1], Minwoo Kim[2], and Ilseok Oh[1,2]

소속: [1]Department of Nano Technology, Chonbuk National University, [2]Department of Computer Engineering Graduate School, Chonbuk National University

**WD4-Q-3** **18:00-18:15** **저전압 TEM 측정을 이용한 그래핀 형상 및 결정립 관찰**

저자: 조영지[1,3], 양준모[1], Do Van Lam[2], 이승모[2], 김재현[2], 박윤창[1], 장지호[3]

소속: [1]나노종합기술원, [2]한국기계연구원, [3]한국해양대학교 응용과학과

**WD4-Q-4** **18:15-18:30** **Accelerating Defect Inspection Technology by Next-Generation Inspection Platforms**

저자: Jeongho Ahn, Shijin Seong, Hyungseop Kim, Dong-Ryul Lee, Heewon Sunwoo, Dong-chul Ihm, and Soobok Chin

소속: Process Development Team, Semiconductor R&D Center, Samsung Electronics Co., Ltd.